IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Luetzen, *et al.*	Docket No.:	INF 2004 SP 00115 US
Serial No.:	10/721,225	Art Unit:	1792
Filed:	November 26, 2003	Examiner:	George A. Goudreau
For:	Method and Structures for Increasing the Structure Density and the Storage Capacitance in a Semiconductor Wafer		

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Submission of Translation of Priority Document

Dear Sir:

Attached is an Accurate Translation of the certified copy of German Patent Application No. 102 55 866.3. Per the Examiner's request, Applicant has included a Statement of Verification with the translation.

Upon review of the originally filed translation, it appears that translation errors may have been made. Any errors in the original translation were not made with deceptive intent. Any differences are not substantive and do not affect the fact that the presently claimed invention is supported by the priority filing.

Respectfully submitted,

September 18, 2008
Date

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